

1792

1110-94326 PATENT



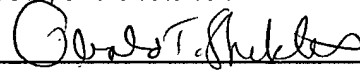
**IN THE UNITED STATES PATENT AND TRADEMARK OFFICE**

App. No. : 10/534,946  
Applicant : YOKOYAMA et al.  
Filed : 11 May 2005  
Art Unit : 1792  
Examiner : SONG, Mathew J.  
Docket No. : 1110-94326  
Customer No. : 24628  
Title : SILICON WAFER, ITS  
MANUFACTURING METHOD, AND ITS  
MANUFACTURING APPARATUS

Confirmation No.: 3657

**CERTIFICATE OF MAILING BY  
FIRST CLASS MAIL (37 CFR 1.8)**

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9 April 2008  
(Date)

**AMENDMENT**

Mail Stop Amendment  
Commissioner for Patents  
P.O. Box 1450  
Alexandria, Virginia 22313-1450

Dear Sir:

The Office Action of January 10, 2008 has been carefully reviewed and the following amendments and remarks are made in response thereto: